

<b>INFORMATION DISCLOSURE STATEMENT PTO-1449</b>	Attv. Docket No. 042068	Serial No. New Appln. w/ 772 253
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	Filing Date: February 6, 2004	Group Art Unit: 2823

### U.S. PATENT DOCUMENTS

Examiner Initial	Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
	AA					
	AB					
	AC					
	AD					

### FOREIGN PATENT DOCUMENTS

Document No.	Date	Country	Translation (Yes or No)		
wp	AE	9-53188	02/25/97	Japan	Abstract & Discussed in the Spec.
	AF				
	AG				
	AH				
	AI				

### OTHER DOCUMENTS

wp	AJ	Jpn. J. Appl. Phys. Vol. 36 (1997) pp. L154-L157, Part 2, No. 2A, 1 February 1997
	AK	Takeshi OHWAKI et al., Preferred Orientation in Ti Films Sputter-Deposited on SiO2 Glass: The Role of Water Chemisorption on the Substrate
Examiner <i>Pham Thanh</i>		Date Considered 6/24/2005